



REPLY UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
HONGO, T.

Application No.: 09/536,721

Confirmation No. 5386

Filed: March 28, 2000

Group: 1763

Title: MICROWAVE PLASMA PROCESSING APPARATUS FOR  
CONTROLLING A TEMPERATURE OF A WAVELENGTH  
REDUCING MEMBER

Examiner: CROWELL, A.

\* \* \* \*

October 17, 2003

REQUEST FOR RECONSIDERATION

Hon. Commissioner of Patents  
Washington, DC 20231

Sir:

RECEIVED  
OCT 21 2003  
TC 1700

Responsive to the Office Action dated September 5, 2003, reconsideration and allowance of the present application based on the following remarks are respectfully requested.